

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. .... 10/128,933  
Priority Filing Date ..... April 23, 2002  
 Inventor ..... Werner Juengling  
 Assignee ..... Micron Technology, Inc.  
Priority Group Art Unit ..... 2822  
Priority Examiner ..... J.L. Brophy  
 Attorney's Docket No. .... MI22-2391  
 Title: Semiconductor Processing Methods Of Forming A Contact Opening To A  
 Conductive Line and Methods of Forming Substrate Active Area Source/Drain  
 Regions

**INFORMATION DISCLOSURE STATEMENT**

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 10/128,933, filed April 23, 2002, upon which the above-identified application relies for a priority date under 35 U.S.C. §120. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. §1.98(d) and MPEP §609(2). Copies of the articles only are submitted for Examiner's convenience.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: 10-3-03

  
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 D. Brent Kenady  
 Reg. No. 40,045

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. M122-2391		SERIAL NO.	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Werner Juengling			
					FILING DATE		GROUP	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,821,140	10/13/98	Jost et al.				
	AB	5,017,506	05/21/91	Shen et al.				
	AC	6,177,339 B1	01/23/01	Juengling				
	AD	5,985,711	11/16/99	Lim				
	AE	5,856,227	01/05/99	Yu et al.				
	AF	5,731,236	03/24/98	Chou et al.				
	AG	5,668,065	09/16/97	Lin				
	AH	5,637,525	06/10/97	Dennison				
	AI	5,459,085	10/17/95	Pasen et al.				
	AJ	4,734,383	03/29/88	Ikeda et al.				
	AK	4,343,657	08/10/82	Ito et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AR		Microchip Fabrication - Second Edition , McGraw-Hill ©1990, page 332 only.					
	AS		Wolf, Ph.D. et al., Silicon Processing for the VLSI Era - Vol. 1 - Process Technology, ©1986, page 283 only.					
	AT							
EXAMINER					DATE CONSIDERED			
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					FILING DATE		GROUP	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	4,232,439	11/11/80	Shibata				
	AB	6,015,730	01/18/00	Wang et al.				
	AC	5,731,242	03/24/98	Parat et al.				
	AD	6,025,255	02/15/00	Chen				
	AE	5,795,809	08/18/98	Gardner et al.				
	AF	5,766,992	06/16/98	Chou et al.				
	AG	5,686,324	11/11/97	Wang et al.				
	AH	5,656,520	08/12/97	Watanabe				
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	AJ	6,337,261	01/08/02	Juengling				
	AK	6,093,629	07/25/00	Chen				
	AL	5,206,187	04/27/93	Doan et al.				
	AM	5,015,594	05/14/91	Chu et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AN							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AO							
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